

Appl. No.: 10/060,826  
Amdt. Dated: 4/27/2004  
Off. Act. Dated: 10/27/2003

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. (original) A matching network for coupling an RF power supply to an RF antenna in a plasma generator, comprising:
  - a resonantly tunable circuit formed of a variable capacitor and an inductor in a series resonance configuration;
  - a ferrite core transformer coupled to the resonantly tunable circuit.
2. (original) The matching network of Claim 1 wherein the transformer comprises a secondary winding which couples the transformer to the tunable circuit and a primary winding.
3. (original) The matching network of Claim 2 wherein the secondary winding is a single-turn winding and the primary winding is a multi-turn winding.
4. (original) The matching network of Claim 3 wherein the transformer further comprises a core which is made of a plurality of ferrite cores.
5. (original) The matching network of Claim 2 wherein the transformer further comprises a core which is made of a plurality of ferrite cores.
6. (original) The matching network of Claim 2 wherein the turn ratio between the primary winding and the secondary winding ranges from 3:1 to 8:1.
7. (original) The matching network of Claim 6 wherein the turn ratio between the

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primary winding and the secondary winding is selected to transform the plasma impedance of the plasma generator to  $50\Omega$ .

8. (original) The matching network of Claim 6 wherein the transformer comprises a core made of 12 ferrite cores with a 1.25 inch OD and 0.75 inch ID, made of M-type ferrite.

9. (original) The matching network of Claim 8 wherein the variable capacitor has a capacity range of 5-125pF.

10. (original) The matching network of Claim 9 wherein the network fits within a cylindrical volume 6 inches in diameter and 8 inches long.

11. (original) The matching network of Claim 1 further comprising an RF power supply connected through a  $50\Omega$  coaxial cable to an input of the matching network and an RF antenna (inductive coil) connected to an output of the matching network.

12. (original) A plasma ion or electron source, comprising:  
an RF power supply;  
a coaxial cable connected to the RF power supply;  
a matching network having an input connected to the coaxial cable, the matching network comprising:  
a resonantly tunable circuit formed of a variable capacitor and an inductor in a series resonance configuration;  
a ferrite core transformer coupled to the resonantly tunable circuit;  
an RF antenna connected to an output of the matching network;  
a plasma ion or electron generator having the RF antenna mounted therein for inductively generating a plasma.

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13. (original) The plasma ion or electron source of Claim 12 wherein the transformer comprises a secondary winding which couples the transformer to the tunable circuit and a primary winding.

14. (original) The plasma ion or electron source of Claim 13 wherein the secondary winding is a single-turn winding and the primary winding is a multi-turn winding.

15. (original) The plasma ion or electron source of Claim 14 wherein the transformer further comprises a core which is made of a plurality of ferrite cores.

16. (original) The plasma ion or electron source of Claim 14 wherein the turn ratio between the primary winding and the secondary winding ranges from 3:1 to 8:1

17. (original) The plasma ion or electron source of Claim 14 wherein the coaxial cable has an impedance of  $50\Omega$  and the turn ratio between the primary winding and the secondary winding is selected to transform the plasma impedance of the plasma generator to  $50\Omega$ .

18. (original) The plasma ion or electron source of Claim 12 wherein the plasma ion or electron generator is a multicusp plasma generator.

19. (original) The plasma ion or electron source of Claim 18 wherein the source is a part of a compact focused ion beam system.

20. (original) The plasma ion or electron source of Claim 19 wherein the matching network fits within a cylindrical cavity 6 inches in diameter and 8 inches long.